P.T.O.

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SARDAR PATEL UNIVERSITY

M.Sc. (Physics)(IIIrd Semester) Examination

Date: 12/04/2018, Day: Thursday, Time: 10:00am to 1:00pm

Subject: Nanoscience and Thin film Physics, Paper No. PS03CPHY02

CBCS(choice based credit system)

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nso the	• appropriate options f	rom the follo	nuina in O I	Total Mark
73C 171C	uppropritire options j	i om me jone	wing in O.1	(8)
i)	radius 10 μm serves		which needle from comagnetic pick up? (c) quartz	, ,
ii)	_	_	oalescence of compos gle (c) thickness	ite island ? (d) mass
iii)		•	which technique you w (c) DC sputtering	vill prefer (d) PECVD
iv)		que is good f) LECVD	or depositing epitaxia (c)PECVD	thin film. (d) HTVCD
v)	From the following which technique is used for formation of carbon nanotubes (a)Ball milling (b)sol-gel (c)co-precipitation (d) laser ablation			
vi)	In infrared detectors, the responsivity of the detector is measured in terms of which of the below quantity generated per watt of incoming radiation. (a) electric current (b) temperature (c) voltage (d) pressure			
vii)			cannot be detected wi	
viii)	•		. ,	(4) 110
		b) 2 MeV	(c) 2GeV	(d) 2eV

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- i) Which two modes are used in TEM for obtaining an image? Write in two lines how these two modes work.
- ii) State the basic principle of Raman Spectroscopy.
- iii) What is sputtering? How magnetic field is used to enhance the sputtering yield? Is there any other way to do so? Explain.
- iv) Define the terms adsorption, desorption and thermal accommodation.
- v) How one can obtain a better XRD pattern of ultra thin film?
- vi) Differentiate between capillarity and atomistic model.
- vii) .What is LEED and RHEED? Which of them is used for insitu thin film characterization.
- viii) Explain photolytic and pyrolytic process of LECVD technique.
- ix) How secondary ion mass spectrometry works?
- Q.3(a) Describe principle, construction and working of atomic force microscope with proper diagrams. (6)
- Q.3(b) Discuss sol-gel method and laser ablation technique by which (6) nanostructures can be formed at the laboratory scale.

OR ---

- Q.3(b) By drawing the lay out diagram explain how scanning tunneling (6) microscope can be used to observe the surface details at atomic scale.
- Q.4(a) Discuss nucleation, island, channel and continuous film growth stages (6) involved in the growth of thin films.
- Q.4(b) Explain QCTM and stylus profilometry methods by which thickness of (6) thin films can be determined.

OR

Q.4(b) What is lithography? Discuss photo, X-ray and e-beam lithography with (6) their limitations.

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- What is epitaxy? State different epitaxy techniques known to you for Q.5(a)depositing films and describe the one which is having lowest deposition How ionized cluster beam deposition technique is used for depositing thin Q.5(b)films? State its applications and merits. (6)Q.5(b) Explain PECVD and MOCVD techniques in detail. Discuss Rutherford back scattering technique with its basic principle. (6) Q.6(a) Q.6(b) Describe the construction and working of scanning electron microscope. (6)OR Q.6(b) How Auger electron spectroscopy can be used to evaluate chemical make (6) up of the constituents of thin film specimen under observation.
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